The following listing of claims will replace all prior versions, and listings, of claims in the application:

## **Listing of Claims:**

1. (Amended) A polymer having silicon-containing groups of the general formula (1):

wherein

one of  $R^1$  and  $R^2$  is a to  $R^4$  each are independently hydrogen or a straight, branched or cyclic alkyl group of 1 to 20 carbon atoms and the other is hydrogen or a straight. branched or cyclic alkyl group of 1 to 20 carbon atoms, or  $R^1$  and  $R^2$ , taken together, may form an aliphatic hydrocarbon ring in which - $CH_2$ - may be substituted with a - $Si(R^8)_2$ - group, and  $R^3$  and  $R^4$  each are independently hydrogen or a straight, branched or cyclic alkyl group of 1 to 20 carbon atom, or  $R^3$  and  $R^4$ , taken together, may form an aliphatic hydrocarbon ring in which - $CH_2$ - may be substituted with a - $Si(R^8)_2$ - group,

R<sup>5</sup> to R<sup>7</sup> each are independently a straight, branched or cyclic alkyl or fluorinated alkyl group of 1 to 20 carbon atoms or aryl group of 6 to 20 carbon atoms,

R<sup>8</sup> is independently a straight or branched alkyl group of 1 to 4 carbon atoms, and m is 1 or 2.

2. (Amended) A The polymer of claim 1, wherein said polymer contains carboxylic acid, alcohol, or phenol groups or combinations thereof, and hydrogen atoms of hydroxyl groups on at least on one of said a carboxylic acid, alcohol or phenol groups is are substituted with the silicon-containing group groups of the general formula (1).

3. (Amended) A polymer comprising recurring units of one of the general formulae (2) to (5):

wherein

one of  $R^1$  and  $R^2$  is a to  $R^4$  each are independently hydrogen or a straight, branched of cyclic alkyl group of 1 to 20 carbon atoms and the other is hydrogen or a straight, branched or cyclic alkyl group of 1 to 20 carbon atoms, or  $R^1$  and  $R^2$ , taken together, may form an aliphatic hydrocarbon ring in which - $CH_2$ - may be substituted with a - $Si(R^8)_2$ - group, and  $R^3$  and  $R^4$  each are independently hydrogen or a straight, branched or cyclic alkyl group of 1 to 20 carbon atom, or  $R^3$  and  $R^4$ , taken together, may form an aliphatic hydrocarbon ring in which - $CH_2$ - may be substituted with a - $Si(R^8)_2$ - group,

R<sup>5</sup> to R<sup>7</sup> each are independently a straight, branched or cyclic alkyl or fluorinated alkyl group of 1 to 20 carbon atoms or aryl group of 6 to 20 carbon atoms,

R<sup>8</sup> is independently a straight or branched alkyl group of 1 to 4 carbon atoms,

 $R^9$  is hydrogen, a straight, branched or cyclic alkyl group of 1 to 20 carbon atoms, or  $CH_2CO_2R^{12}$ ,

R<sup>10</sup> is hydrogen or a straight, branched or cyclic alkyl group of 1 to 20 carbon atoms,



R<sup>11</sup> is a straight, branched or cyclic alkylene group of 1 to 10 carbon atoms, R<sup>12</sup> is hydrogen or a straight, branched or cyclic alkyl group of 1 to 20 carbon atoms, m is 1 or 2, n is a number of 0 to 5, p is a number of 1 to 5, each of q and r is 0 or 1.

- 4. (Original) A chemically amplified positive resist composition comprising:
  - (A) the polymer of claim 1,
  - (B) a photoacid generator, and
  - (C) an organic solvent.
- 5. (Original) The resist composition of claim 4 further comprising a basic compound.
- 6. (Original) A chemically amplified positive resist composition comprising:
  - (A) the polymer of claim 1,
  - (B) a photoacid generator,
  - (C) an organic solvent, and
  - (D) a dissolution rate inhibitor having an acid labile group.
- 7. (Original) The resist composition of claim 6 further comprising a basic compound.
- 8. (Amended) A process for forming a pattern, comprising the steps of: applying <u>a</u> the positive resist composition of claim 4 onto an organic film on a substrate to form a coating,

prebaking the coating to form a resist film, exposing the resist film in a pattern circuit region to radiation, post-exposure baking the resist film,

developing the resist film with an aqueous alkaline solution to dissolve away the exposed area, thereby forming a resist pattern, and

processing the organic film with an oxygen plasma generated by a dry etching apparatus.

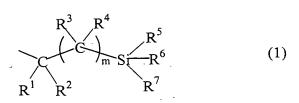


(New) A chemically amplified positive resist composition comprising:(A) the polymer of claim 3,

- (B) a photoacid generator, and
- (C) an organic solvent.



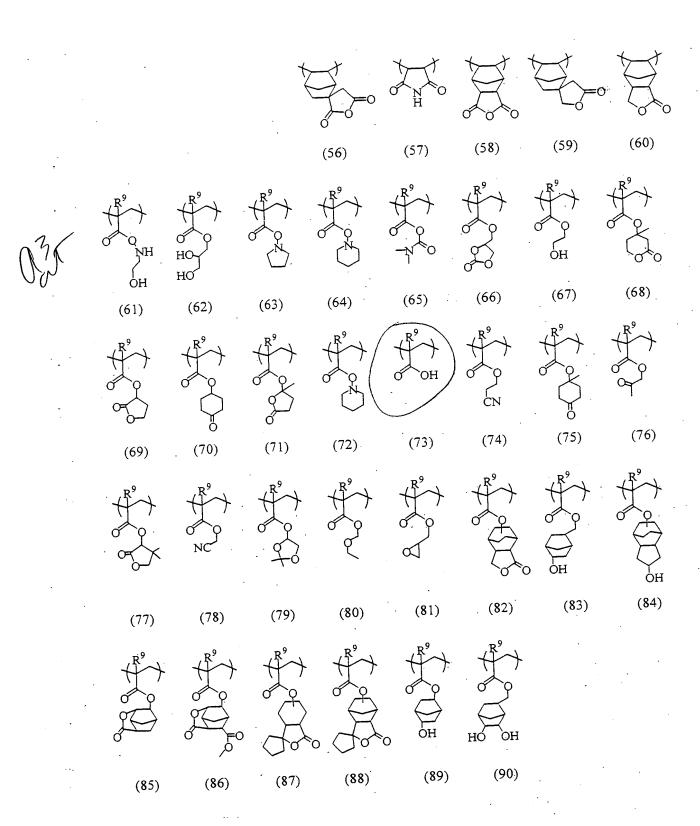
- 10. (New) A resist composition of claim 9, further comprising a basic compound.
- 11. (New) A chemically amplified positive resist composition comprising:
  - (A) the polymer of claim 3,
  - (B) a photoacid generator,
  - (C) an organic solvent, and
  - (D) a dissolution rate inhibitor having an acid labile group.
- 12. (New) A resist composition of claim 11, further comprising a basic compound.
- 13. (New) A polymer having silicon-containing groups of formula (1) and recurring units of at least one of formulae (56) to (90):



wherein  $R^1$  to  $R^4$  each are independently hydrogen or a straight, branched or cyclic alkyl group of 1 to 20 carbon atoms, or  $R^1$  and  $R^2$ , taken together, optionally form an aliphatic hydrocarbon ring in which -CH<sub>2</sub>- is optionally substituted by -Si( $R^8$ )<sub>2</sub>- group, and  $R^3$  and  $R^4$ , taken together, optionally form an aliphatic hydrocarbon ring in which -CH<sub>2</sub>- is optionally substituted by -Si( $R^8$ )<sub>2</sub>-,

R<sup>5</sup> to R<sup>7</sup> each are independently a straight, branched or cyclic alkyl or fluorinated alkyl group of 1 to 20 carbon atoms or an aryl group of 6 to 20 carbon atoms,

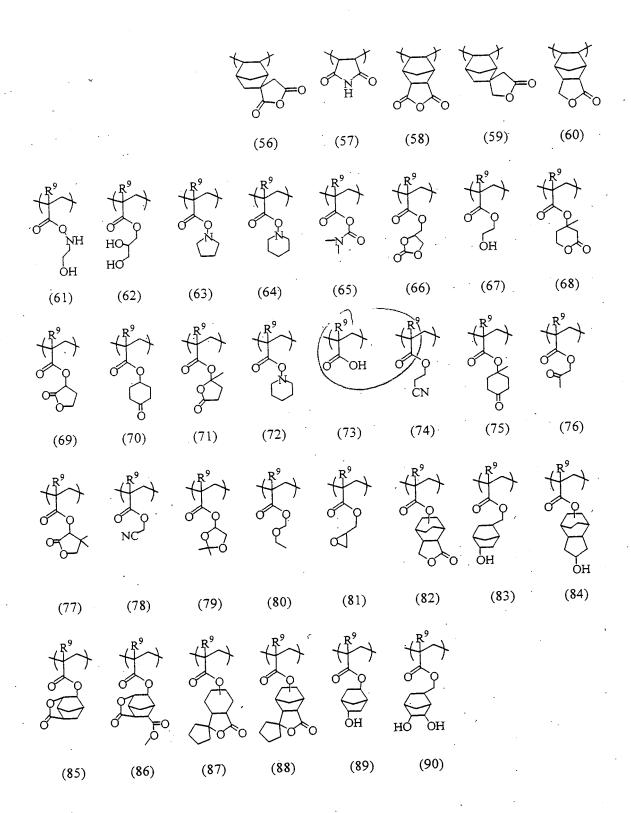
R<sup>8</sup> is independently a straight or branched alkyl group of 1 to 4 carbon atoms, and m is 1 or 2,



wherein  $R^9$  is hydrogen, a straight, branched or cyclic  $C_{1-20}$  alkyl group, or  $CH_2CO_2R^{12}$ , and  $R^{12}$  is hydrogen or a straight, branched or cyclic  $C_{1-20}$  alkyl group.

14. (New) A polymer comprising recurring units of one of formula (2) to (5) and recurring uints of (56) to (90):

$$\begin{array}{c}
 & R^9 \\
 & R^{10} \\$$



wherein

 $R^1$  to  $R^4$  each are independently hydrogen or a straight, branched or cyclic alkyl group of 1 to 20 carbon atoms, or  $R^1$  and  $R^2$ , taken together, optionally form an aliphatic

hydrocarbon ring in which -CH<sub>2</sub>- is optionally substituted by -Si( $R^8$ )<sub>2</sub>- group, and  $R^3$  and  $R^4$ , taken together, optionally form an aliphatic hydrocarbon ring in which -CH<sub>2</sub>- is optionally substituted by -Si( $R^8$ )<sub>2</sub>-,

R<sup>5</sup> to R<sup>7</sup> each are independently a straight, branched or cyclic alkyl or fluorinated alkyl group of 1 to 20 carbon atoms or an aryl group of 6 to 20 carbon atoms,

R<sup>8</sup> is independently a straight or branched alkyl group of 1 to 4 carbon atoms,

R<sup>9</sup> is hydrogen, a straight, branched or cyclic C<sub>1-20</sub> alkyl group, or CH<sub>2</sub>CO<sub>2</sub>R<sup>12</sup>,

R<sup>10</sup> is hydrogen or a straight, branched or cyclic C<sub>1-20</sub> alkyl group,

R<sup>11</sup> is a straight, branched or cyclic C<sub>1-10</sub> alkylene group,

R<sup>12</sup> is hydrogen or a straight, branched or cyclic C<sub>1-20</sub> alkyl group,

m is 1 or 2,

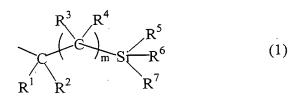
n is a number of 0 to 5,

p is a number of 1 to 5, and

each of q and r is 0 or 1.

- 15. (New) A chemically amplified positive resist composition comprising:
  - (A) the polymer of claim14,
  - (B) a photoacid generator, and
  - (C) an organic solvent.
- 16. (New) A resist composition of claim 15, further comprising a basic compound.
- 17. (New) A chemically amplified positive resist composition comprising:
  - (A) the polymer of claim 14,
  - (B) a photoacid generator,
  - (C) an organic solvent, and
  - (D) a dissolution rate inhibitor having an acid labile group.
- 18. (New) A resist composition of claim 17, further comprising a basic compound.
- 19. (New) A monomer having silicon-containing groups of formula (1):







wherein  $R^1$  to  $R^4$  each are independently hydrogen or a straight, branched or cyclic alkyl group of 1 to 20 carbon atoms, or  $R^1$  and  $R^2$ , taken together, optionally form an aliphatic hydrocarbon ring in which -CH<sub>2</sub>- is optionally substituted by -Si( $R^8$ )<sub>2</sub>- group, and  $R^3$  and  $R^4$ , taken together, optionally form an aliphatic hydrocarbon ring in which -CH<sub>2</sub>- is optionally substituted by -Si( $R^8$ )<sub>2</sub>-,

R<sup>5</sup> to R<sup>7</sup> each are independently a straight, branched or cyclic alkyl or fluorinated alkyl group of 1 to 20 carbon atoms or an aryl group of 6 to 20 carbon atoms,

R<sup>8</sup> is independently a straight or branched alkyl group of 1 to 4 carbon atoms, and m is 1 or 2.

20. (New) A monomer capable of forming units of one of formulae (2) to (5):

wherein

 $R^1$  to  $R^4$  each are independently hydrogen or a straight, branched or cyclic alkyl group of 1 to 20 carbon atoms, or  $R^1$  and  $R^2$ , taken together, may form an aliphatic hydrocarbon ring in which -CH<sub>2</sub>- may be substituted with a

 $-Si(R^8)_{2^-}$  group, and  $R^3$  and  $R^4$ , taken together, may form an aliphatic hydrocarbon ring in which  $-CH_{2^-}$  may be substituted with a  $-Si(R^8)_{2^-}$  group,

 $R^5$  to  $R^7$  each are independently a straight, branched or cyclic alkyl or fluorinated alkyl group of 1 to 20 carbon atoms or aryl group of 6 to 20 carbon atoms,

R<sup>8</sup> is independently a straight or branched alkyl group of 1 to 4 carbon atoms,

 $R^9$  is hydrogen, a straight, branched or cyclic alkyl group of 1 to 20 carbon atoms, or  $CH_2CO_2R^{12}$ ,

R<sup>10</sup> is hydrogen or a straight, branched or cyclic alkyl group of 1 to 20 carbon atoms,



 $R^{11}$  is a straight, branched or cyclic alkylene group of 1 to 10 carbon atoms,  $R^{12}$  is hydrogen or a straight, branched or cyclic alkyl group of 1 to 20 carbon atoms, m is 1 or 2, n is a number of 0 to 5, p is a number of 1 to 5, each of q and r is 0 or 1.